

Docket #: S01-227

NanoGap

A method of fabricating a variable capacitive device for micromachined sensors and actuators. A critical optimization of these capacitors for both sensing and actuation is achieved by maximizing the capacitance change with gap width or overlap area. This process can be used to build simple facing capacitors, integrated capacitors, and the differential inter-digitated capacitors.

Applications

- MEMS
- Sensors
- Actuators
- Capacitors

Advantages

- Significantly finer gap width is achieved through this method compared to common etched process.

Patents

- Published Application: [20040209435](#)
- Published Application: [WO2004095540](#)

Innovators

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